

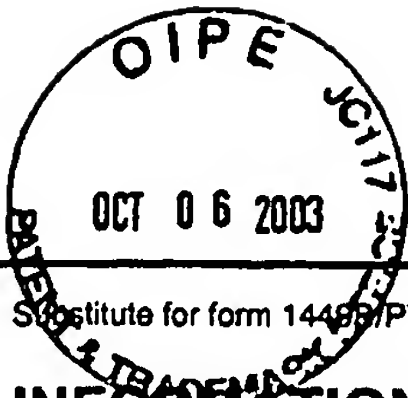
PTO/SB/08A (08-03)

INFORMATION DISCLOSURE STATEMENT BY APPLICANT (use as many sheets as necessary)		Complete if Known			
		Application Number	10/632,662		
		Filing Date	August 1, 2003		
		First Named Inventor	Staple, Bevan		
		Art Unit			
Sheet	1	of	3	Examiner Name	
				Attorney Docket Number	019930-003110US

U.S. PATENT DOCUMENTS+					
Examiner Initials*	Cite No. ¹	Document Number Number Kind Code ² (if known)	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
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Examiner Signature	<i>Michelle R. Connelly-Cuthwa</i>	Date Considered	3/4/04
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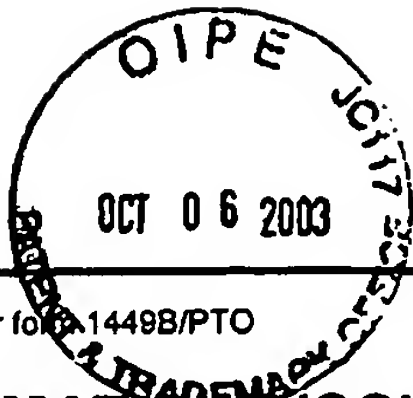
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Sheet	2	of	3	Attorney Docket Number	019930-003110US

NON PATENT LITERATURE DOCUMENTS			
Examiner Initials *	Cite No. ¹	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T ²
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Examiner Signature	<i>Michael R. Connelly</i>	Date Considered	3/4/04
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Examiner Signature	<i>Michelle R. Connolly</i>	Date Considered	3/4/04
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